

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Takenori HIROSE et al.

Serial No.: Not yet assigned – Continuation of Serial No. 09/622,570

Filed: Even date herewith

For: **A THIN FILM THICKNESS MEASURING METHOD AND APPARATUS,
AND METHOD AND APPARATUS FOR MANUFACTURING A THIN
FILM DEVICE USING THE SAME**

Group: 2873 (expected)

Examiner: Jack Dinh (expected)

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

November 13, 2003

Sir:

Prior to examination of the above-identified application, please amend the
specification as follows:

Amendments to the Specification begin on page 2 of this paper.

Remarks/Arguments begin on page 3 of this paper.